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LIGA

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(MEMS)

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UV

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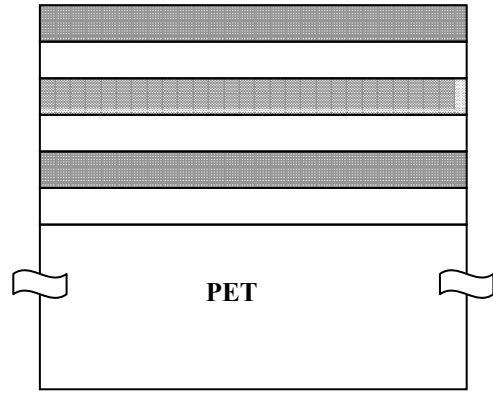
(DCM)

X

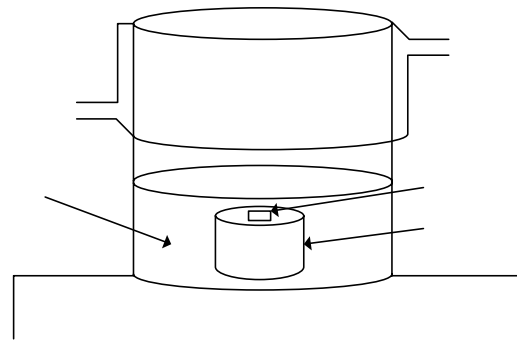
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DMF

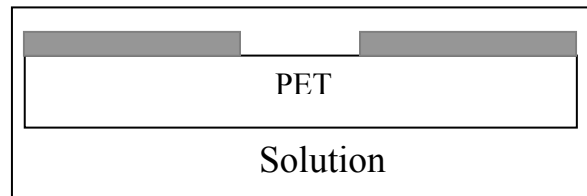
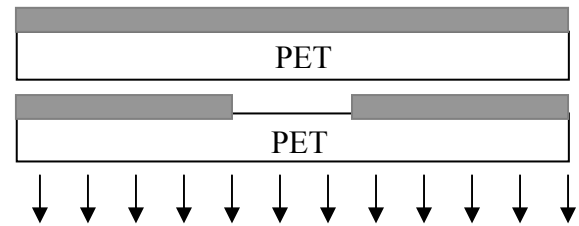
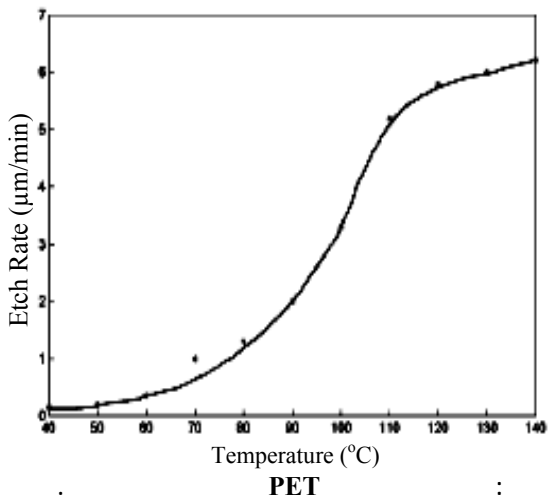
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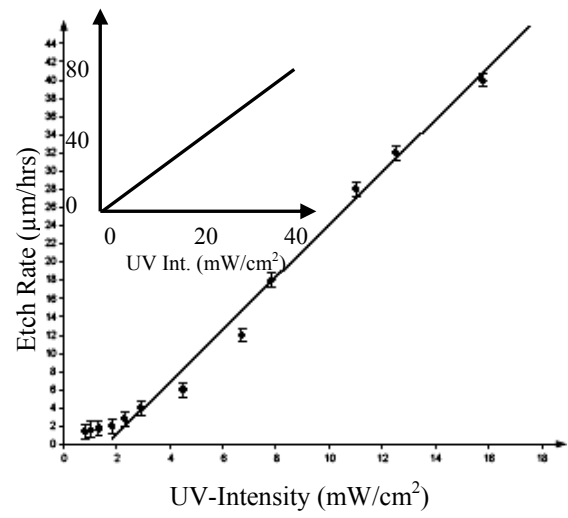
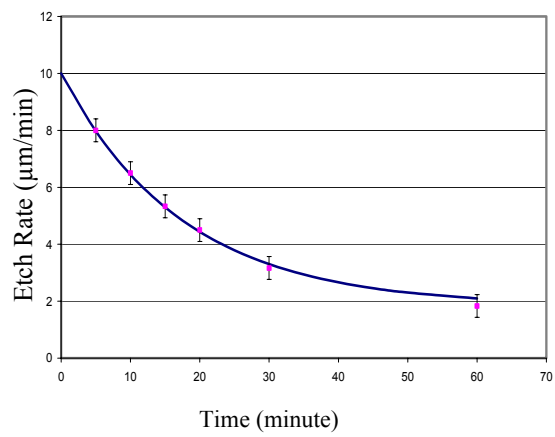
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UV

$\text{mW}/\text{cm}^2$

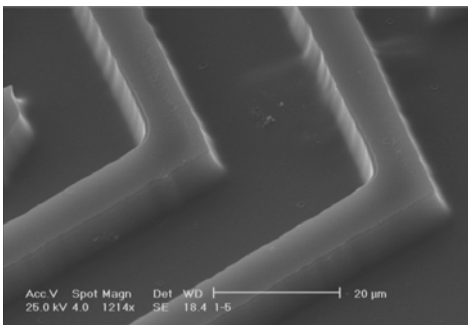
UV



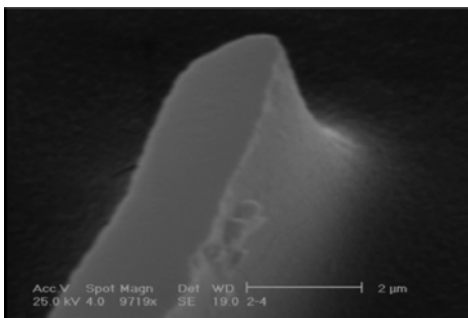
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UV

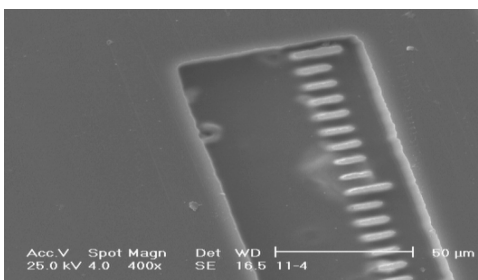
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$$R(t) = (R_0 - R_\infty) \exp(-t/\tau) + R_\infty$$

"t" R(t)  
τ R∞ R0

/ R∞ R0

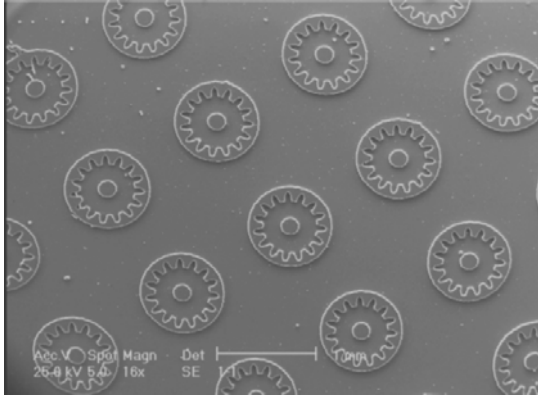
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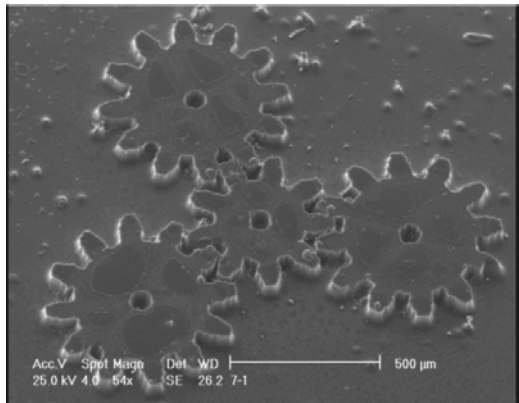
(under-cut)

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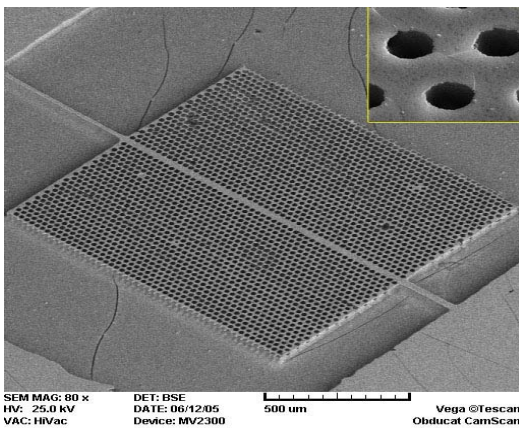


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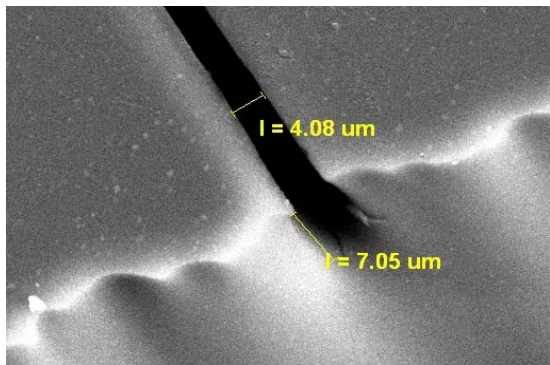
(Dek-Tak 3B)

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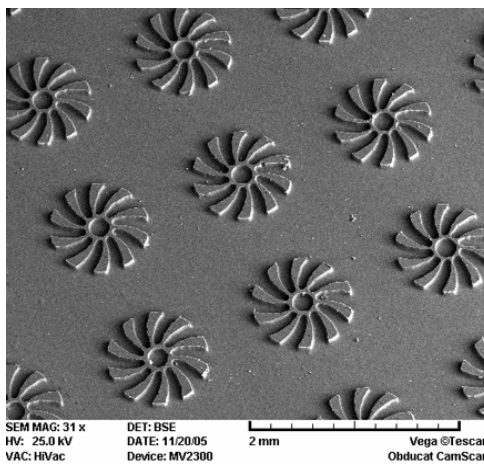
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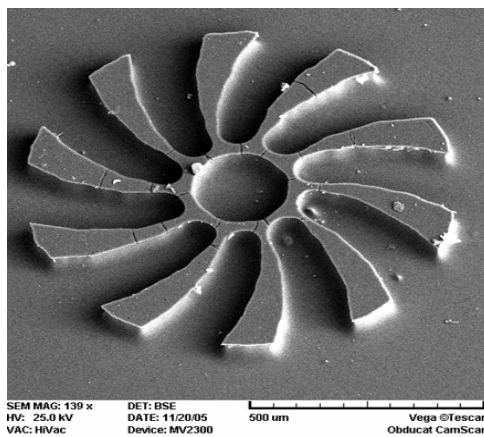
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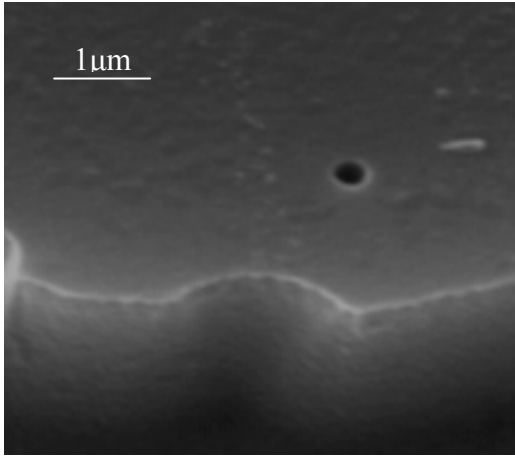


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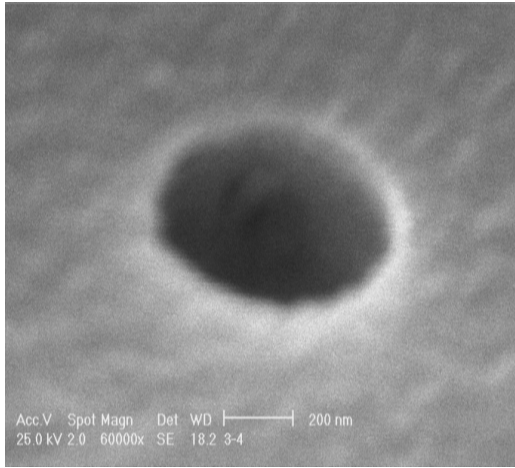


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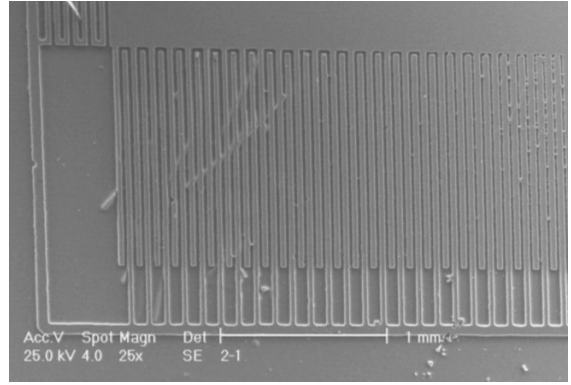
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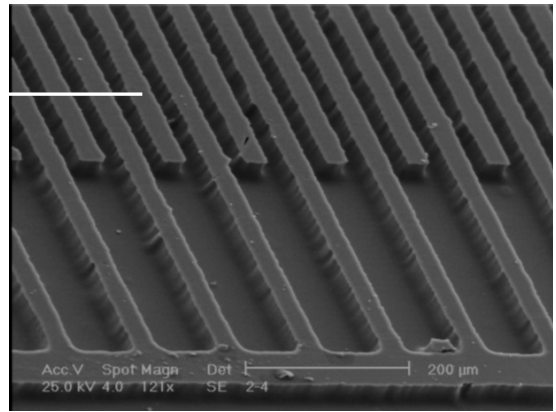
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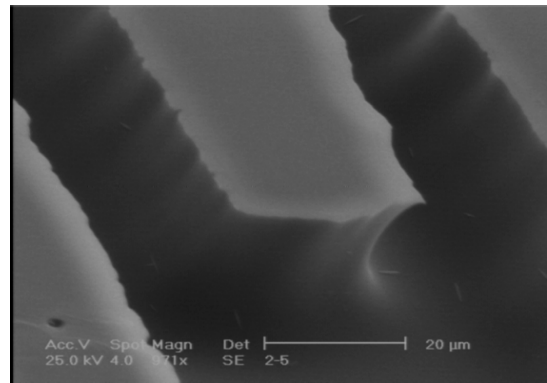
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UV

- 1 - Alavi, M., Schumacher, A. and Wagner, H. J. (1991). "Laser machining and anisotropic etching of <111> silicon for applications in Microsystems." *In Proc. Micro Syst. Technol.*, PP. 227–231.
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- 1 - UV-curable adhesive
  - 2 - Poly-Ethylene Terephthalate
  - 3 - Di-Methyl-Formamide
  - 4 - Di-Chloromethane
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